

Fabrication of Vertical Resonant Cavity InGaN LEDs by a Laser Lift-off Technique

黃詩詠、武東星；姚品全

E-mail: 9419807@mail.dyu.edu.tw

ABSTRACT

We present the state-of-the-art resonant-cavity light-emitting diode (RCLED) application to short-haul communication system on plastic optical fiber. The RCLED structure composed of an InGaN/GaN multiple-quantum-well active layer has been grown by metal organic chemical vapor deposition, between the top (5-pairs) and bottom (7.5-pairs) dielectric TiO₂/SiO₂ distributed Bragg reflectors with optical reflectance of 85 and 99.9%, respectively with a larger stopband of 100 nm. It was found that the emission peak (around 525 nm) of RCLED shows more stability and lesser joule heating effect induced red shift were measured with increasing the injection current density. The mode cavity of the RCLED shows a linewidth of 5.5 nm at a main emission peak at 525 nm, while the emission directionality was rather improved than that of the conventional LED. The emission full width at half maximum can decrease from 48 to 35 nm and a quality factor for the structure of approximately $Q \sim 100$. These results indicated that the EL spectrum of the RCLED was found to be modulated strongly due to the effect of the resonant cavity. Nevertheless, the improvement in emission directionality is attributed to the as evidenced by the angle-resolved electroluminescence measurements.

Keywords : GaN、InGaN、Resonant-Cavity Light-Emitting Diode (RCLED)

Table of Contents

封面內頁 簽名頁 授權書	iii	中文摘要	iii
.	iv	英文摘要	v
.	vi	目錄	vii
.	x	第一章 緒論	1
前言	1	1.2 研究背景與動機	3
原理	8	2.1 駐波	8
工作原理	8	2.3 品質因數(Quality Factor)與Finesse參數	11
鏡之工作原理	12	2.5 介電質分佈式布拉格反射鏡之設計原理	14
.	15	第三章 實驗步驟	28
.	28	3.1 實驗流程	28
3.1.1 第一道製程-定義元件尺寸大小(Mesa)	29	3.1.2 第二道製程-透明導電層(Transparent Conductive Layer TCL)	30
3.1.3 第三道製程-絕緣層(Insulating Layer)	31	3.1.4 第四道製程-正負電極(P and N Electrode)	31
3.1.5 第五道製程-雷射剝離製程	32	3.1.6 第六道製程-下介電質分佈式布拉格反射鏡之製作	33
3.1.7 第七道製程-晶圓貼合製程	33	3.1.8 第八道製程-上介電質分佈式布拉格反射鏡之製作	34
(N & K Analyzer)	35	3.3 原子力顯微鏡量測儀(AFM)	35
.	36	3.4 掃描式電子顯微鏡(SEM)	36
.	38	3.5 電性量測系統	37
.	38	3.7 電激發光光譜量測系統(EL)	39
.	51	第四章 實驗結果與討論	51
51 4.1 雷射剝離技術之研討	51	4.1.1 雷射剝離後之氮化鎵表面	51
51 4.1.2 雷射剝離後之氮化鎵表面粗糙度	52	4.1.3 雷射剝離前後光激發光頻譜圖	52
共振腔發光二極體之電特性量測	53	4.3 全介電質共振腔發光二極體之調變上反射率之研討	53
.	53	4.3.1 下介電質薄膜反射率之實際值與模擬值之比較	54
4.3.2 上與下介電質布拉格反射鏡的實際反射率疊圖	55	4.3.3 介電質反射鏡之場發射掃描式電子顯微鏡剖面圖	55
.	55	4.3.4 介電質薄膜表面輪廓及粗糙度	55
.	55	4.4 全介電質共振腔發光二極體之電激發光曲線圖之研討	56
4.5 全介電質共振腔發光二極體之變溫量測分析	57	4.6 全介電質共振腔發光二極體之電流密度對半高寬曲線圖之研討	57
.	57	4.7 全介電質共振腔發光二極體之電流密度對波長曲線圖之研討	58
.	58	4.8 全介電質共振腔發光二極體之光輻射角度對電激發光強度曲線圖之研討	59
.	59	4.9 全介電質共振腔發光二極體之電流密度對光輸出功率之研討	60
.	60	4.10 全介電質共振腔發光二極體之可信賴度分析	60
.	81	第五章 結論	81
.	81	參考文獻	82

REFERENCES

- 【1】 H. Amano, T. Asahi, and I. Akasaki, " Stimulated Emission Near Ultraviolet at Room Temperature from a GaN Film Grown on Sapphire by MOVPE Using an AlN Buffer Layer, " *Jpn. J. Appl. Phys.*, vol. 29, no.2, pp. L205-L206, Feb. 1990. 【2】 S. Strite, and H. Morkoc, " GaN, AlN, and InN: A Review, " *J. Vac. Sci. Technol.* vol. B10, no. 4, pp. 1237-1266, Jul/Aug 1992. 【3】 F. Calle1, F. B. Naranjo, S. Ferna ' ndez, M. A. Sa ' nchez-Garci ' a, E. Calleja, and E. Mun?oz, " Nitride RCLEDs Grown by MBE for POF Applications, " *phys. stat. sol. (a)* vol. 192, no. 2, pp. 277-285, March 2002. 【4】 E. F. Schubert, Y.-H. Wang, A. Y. Cho, L.-W. Tu, and G. J. Zydzik, " Resonant Cavity Light-Emitting Diode, " *Appl. Phys. Lett.*, vol. 60, no. 8, pp. 921-923, Feb. 1992. 【5】 P. Maaskant, M. Akhter, B. Roycroft, E. O ' Carroll, and B. Corbett, " Fabrication of GaN-Based Resonant Cavity LEDs, " *Phys. Stat. Sol. (a)* vol. 192, no. 2, pp. 348-353, 2002. 【6】 B. Roycroft, M. Akhter, P. Maaskant, P. de Mierry, S. Ferna ' ndez, F. B. Naranjo, E. Calleja, T. McCormack, and B. Corbett, " Experimental Characterisation of GaN-Based Resonant Cavity Light Emitting Diodes, " *Phys. Stat. Sol. (a)* vol. 192, no. 1, pp. 97-102, 2002. 【7】 T. Honda, A. Katsube, T. Sakaguchi, F. Koyama, and K. Iga, " Threshold Estimation of GaN-Based Surface Emitting Lasers Operating in Ultraviolet Spectral Region, " *Jpn. J. Appl. Phys.*, vol. 34, no.7A, pp. 3527-3532, July 1995. 【8】 S. P. DenBaars, " Blue and Green InGaN VCSEL Technology, " Department of Materials University of California, Santa Barbara, California, 93106, Final Report 1998-99 for MICRO Project 98-034. 【9】 Y.-K. Song, H. Zhou, M. Diagne, I. Ozden, A. Vertikov, and A. V. Nurmikko, " A Vertical Cavity Light Emitting InGaN Quantum Well Heterostructure, " *Appl. Phys. Lett.* vol. 74, no. 23, pp. 3441-3443, Jun. 1999. 【10】 Y.-K. Song, M. Diagne, H. Zhou, A. V. Nurmikko, R. P. Schneider, Jr., and T. Takeuchi, " Resonant-Cavity InGaN Quantum-Well Blue Light-Emitting Diodes, " *Appl. Phys. Lett.* vol. 77, no. 12, pp. 1744-1746, Sep. 2000. 【11】 H. Benisty, H. De Neve, and C. Weisbuch, " Impact of Planar Microcavity Effects on Light Extraction—Part I: Basic Concepts and Analytical Trends, " *IEEE J. Quantum Electron.*, vol. 34, no. 9, pp. 1612-1631, Sep. 1998. 【12】 A. Furukawa, S. Sasaki, M. Hoshi, A. Matsuzono, K. Moritoh, and T. Baba, " High-Power Single-Mode Vertical-Cavity Surface-Emitting Lasers, " *Appl. Phys. Lett.* vol. 85, no. 22, pp. 5161-5163, Nov. 2004. 【13】 I. L. Kresthikov, W. V. Lundin, A. V. Sakharov, V. A. Semenov, A. S. Usikov, A. F. Tsatsul ' nikov, and Zh. I. Alferov, " Room-Temperature Photopumped InGaN/GaN/AlGaIn Vertical-Cavity Surface-Emitting Laser, " *Appl. Phys. Lett.* vol. 75, no. 9, pp. 1192-1194, Aug. 1999. 【14】 B. S. Ryvkin and K. Panajotov, " Optical-Injection-Induced Polarization Switching in Polarization-Bistable Vertical-Cavity Surface-Emitting Lasers, " *J. Appl. Phys.* vol. 96, no. 11, pp. 6002-6007, Dec. 2004. 【15】 F. B. Naranjo, S. Ferna ' ndez, M. A. Sa ' nchez-Garci ' a, F. Calle, and E. Calleja, " Resonant-Cavity InGaN Multiple -Quantum-Well Green Light-Emitting Diode Grown by Molecular-Beam Epitaxy, " *Appl. Phys. Lett.* vol. 80, no. 12, pp. 2198-2200, Mar. 2002. 【16】 P. de Mierry, J. M. Bethoux, H. P. D. Schenk, M. Vaille, E. Feltin, B. Beaumont, M. Leroux, S. Dalmaso, and P. Gibart, " Vertical Cavity InGaIn LEDs Grown by MOVPE, " *Phys. Stat. Sol. (a)* vol. 192, no. 2, pp. 335-340, 2002. 【17】 M. Arita, M. Nishioka, and Y. Arakawa, " InGaIn Vertical Microcavity LEDs with a Si-Doped AlGaIn/GaN Distributed Bragg Reflector, " *Phys. Stat. Sol. (a)* vol. 194, no. 2, pp. 403-406, 2002. 【18】 P.N. Stavrinou, et al., " Insight into Planar Microcavity Emission as a Function of Numerical Aperture, " *Opt. Commun.* vol. 195, pp. 327-338, Aug 2001. 【19】 A. M. Green., D. G. Gevaux, C. Roberts, C. C. Phillips, " Resonant-Cavity-Enhanced Photodetectors and LEDs in the Mid-Infrared, " *Phys. E*, vol.20, pp. 531-535, 2004. 【20】 李正中編著, "薄膜光學與鍍膜技術", 藝軒圖書出版社 【21】 S. Sano, T. Detchprohm, S. Mochizuki, S. Kamiyama, H. Amano and I. Akasaki, " Low-Dislocation-Density GaN and AlxGa1-xN (x 0.13) Grown on Grooved Substrates, " *J. Cryst. Growth*, vol. 235, pp. 129-134, 2002. 【22】 P. R. Tavernier and D. R. Clarke, " Mechanics of Laser-Assisted Debonding of Films, " *J. Appl. Phys.* vol. 89, no. 3, pp. 1527-1536, Feb. 2001. 【23】 T. Ueda, M. Ishida, S. Tamura, Y. Fujimoto, M. Yuri, T. Saito, and D. Ueda, " Vertical InGaIn-Based Blue Light Emitting Diode with Plated Metal Base Fabricated Using Laser Lift-Off Technique, " *phys. stat. sol. (c)* vol. 0, no. 7, pp. 2219-2222, 2003. 【24】 C. F. Chu, F. I. Lai, J. T. Chu, C. C. Yu, C. F. Lin, H. C. Kuo, and S. C. Wang, " Study of GaN Light-Emitting Diodes Fabricated by Laser Lift-Off Technique, " *J. Appl. Phys.* vol. 95, no. 8, pp. 3916-3922, Apr. 2004. 【25】 P. Perlin, L. Mattos, N. A. Shapiro, J. Kruger, W. S. Wong and T. Sands, " Reduction of the Energy Gap Pressure Coefficient of GaN Due To the Constraining Presence of the Sapphire Substrate, " *J. Appl. Phys.* vol. 85, no. 4, pp. 2385-2389, Feb. 1999. 【26】 W. S. Wong, Y. Cho, E. R. Weber, and T. Sands, " Structural and Optical Quality of GaN/Metal/Si Heterostructures Fabricated by Excimer Laser Lift-Off, " *Appl. Phys. Lett.* vol. 75, no. 13, pp. 1887-1889, Sep. 1999. 【27】 W. S. Wong and T. Sands, " Fabrication of Thin-Film InGaIn Light-Emitting Diode Membranes by Laser Lift-Off, " *Appl. Phys. Lett.* vol. 75, no. 10, pp. 1360-1362, Sep. 1999.